

# Yufridin Wahab

## List of Publications by Year in descending order

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33  
papers

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1478505

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times ranked

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citing authors

#	ARTICLE	IF	CITATIONS
1	Current Development in Interdigital Transducer (IDT) Surface Acoustic Wave Devices for Live Cell In Vitro Studies: A Review. <i>Micromachines</i> , 2022, 13, 30.	2.9	24
2	Process development and characterization towards microstructural realization using laser micromachining for MEMS. <i>SN Applied Sciences</i> , 2020, 2, 1.	2.9	2
3	Materialization of MEMS in a collaborative AMBIENCE: A UniMAP experience. , 2016, , .		0
4	From ambient vibrations to green energy source: MEMS piezoelectric energy harvester for low frequency application. , 2015, , .		9
5	Poly-Resistor Thin Film Formation by Excimer Laser Micromachine. <i>Applied Mechanics and Materials</i> , 2015, 780, 17-21.	0.2	0
6	Etch Performance of KRF Excimer Laser Micromachining Characterization on Silicon Material. <i>Applied Mechanics and Materials</i> , 2015, 780, 29-32.	0.2	2
7	Design of Compact Composite Microstrip Low Pass Filter Using MEMS Technology. <i>Applied Mechanics and Materials</i> , 2015, 754-755, 581-590.	0.2	0
8	Hardware Selection for Realization of Ultra-portable Wireless Human Motion Measurement System. <i>Procedia Computer Science</i> , 2014, 42, 62-69.	2.0	0
9	Characterization of MEMS structure on silicon wafer using KrF excimer laser micromachining. , 2014, , .		6
10	The effect of softbaking temperature on SU-8 photoresist performance. , 2014, , .		8
11	Low Power Shoe Integrated Intelligent Wireless Gait Measurement System. <i>Journal of Physics: Conference Series</i> , 2014, 495, 012044.	0.4	11
12	Design and Analysis of Various Microcantilever Shapes for MEMS Based Sensing. <i>Journal of Physics: Conference Series</i> , 2014, 495, 012045.	0.4	9
13	Error Correction for Foot Clearance in Real-Time Measurement. <i>Journal of Physics: Conference Series</i> , 2014, 495, 012046.	0.4	4
14	Development of Interdigitated Electrode Molecular Imprinted Polymer Sensor for Monitoring Alpha Pinene Emissions from Mango Fruit. <i>Procedia Engineering</i> , 2013, 53, 197-202.	1.2	9
15	Development of dye-sensitized solar cell (DSSC) using patterned indium tin oxide (ITO) glass: fabrication and testing of DSSC. , 2013, , .		5
16	Sensory system for detection of Harumanis mango fruit maturity. , 2013, , .		4
17	Modelling of Critical Slopes of Gait Patterns for the Realization of a Wireless Foot Clearance Measurement. , 2013, , .		1
18	Highly selective molecular imprinted polymer (MIP) based sensor array using interdigitated electrode (IDE) platform for detection of mango ripeness. <i>Sensors and Actuators B: Chemical</i> , 2013, 187, 434-444.	7.8	35

#	ARTICLE	IF	CITATIONS
19	Comments and Reply to: Foot Plantar Pressure Measurement System: A Review. Sensors 2012, 12, 9884-9912. Sensors, 2013, 13, 3527-3529.	3.8	1
20	Conversion of UHF Composite Low Pass Filter into Microstrip Line Form. , 2013, , .		2
21	Foot Plantar Pressure Measurement System: A Review. Sensors, 2012, 12, 9884-9912.	3.8	585
22	Recognition of Limonene Volatile Using Interdigitated Electrode Molecular Imprinted Polymer Sensor. , 2012, , .		6
23	Gait analysis measurement for sport application based on ultrasonic system. , 2011, , .		37
24	Microsystem based portable shoe integrated instrumentation using ultrasonic for gait analysis measurement. , 2011, , .		5
25	Silicon implementation of micro pressure sensor. , 2010, , .		1
26	Comparison and silicon realization of custom designed MEMS biomedical pressure sensors. , 2009, , .		6
27	Sensitivity optimization of a foot plantar pressure micro-sensor. , 2008, , .		5
28	Design of MEMS biomedical pressure sensor for gait analysis. , 2008, , .		10
29	Micro-sensor for foot pressure measurement. , 2008, , .		5
30	Analysis of foot-to-ground clearance measurement techniques for MEMS realization. , 2007, , .		4
31	Reduction of Power Dissipation in Dynamic BiCMOS Logic Gates by Transistor Reordering. VLSI Design, 2002, 15, 547-553.	0.5	0
32	Atmospheric Pressure Helium Plasma Treatment on 3C-SiC/Si Surface. Applied Mechanics and Materials, 0, 695, 118-121.	0.2	1
33	KrF Excimer Laser Micromachining of Silicon for Micro-Cantilever Applications. , 0, , .		8